

<div style="display: flex; align-items: center;"> <div style="border: 1px solid black; border-radius: 50%; padding: 10px; margin-right: 10px; text-align: center;"> P E J C 81  NOV 26 2003  (27) </div> <div> <p><b>INFORMATION DISCLOSURE CITATION</b></p> <p><i>(Use several sheets if necessary)</i></p> </div> </div>	Docket Number (Optional) <b>U6090-3</b>		Application Number <b>10/046,594</b>
	Applicant(s) <b>Stephen Y. Chou</b>		
	Filing Date <b>October 29, 2001</b>		Group Art Unit <b>1732</b>


**INFORMATION DISCLOSURE CITATION**  
(Use several sheets if necessary)

[illegible]

## FOREIGN PATENT DOCUMENTS

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	<b>U6090-3</b>	<b>10/046,594</b>
	<b>Applicant(s)</b> <b>Stephen Y. Chou</b>	
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## U.S. PATENT DOCUMENTS

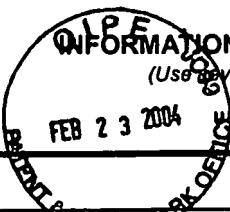
**FOREIGN PATENT DOCUMENTS**

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**Examiner**

**Date Considered**

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				ATTY DOCKET NO. U6090-3		SERIAL NO. 10/046,594	
				Stephen Y. Chou			
FILING October 29, 2001				GROUP 1732			
<b>U.S. PATENT DOCUMENTS</b>							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
MON	5,425,848	06/20/95	Halsma et al.				
↑	5,503,963	04/02/96	Bifano	↑			
	4,543,225	09/24/85	Beaujean				
	5,434,107	07/18/95	Paranjpe				
	5,338,396	08/16/94	Abdala et al.				
	5,471,455	11/28/95	Jabr				
	4,287,235	09/01/81	Flanders				
	4,512,848	04/23/85	Deckman et al.				
MON	5,259,926	11/09/93	Kuwabara et al.				
<b>FOREIGN PATENT DOCUMENTS</b>							
	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>							
MON		Kamins, T.I., "Positioning of Self-Assembled, single-crystal, germanium islands by silicon nanoimprinting" Applied Physics Letter, Vol. 74, No. 12, March 22, 1999					
MON		Wang, J., et al., "Fabrication of a new broadband waveguide polarizer with a double-layer 190 nm period metal-gratings using nanoimprint lithography" J. Vac. Sci. Technol. B 17 (6) Nov/Dec 1999.					
EXAMINER M. Vargot			DATE CONSIDERED 7/2/07				

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<b>Stephen Y. Chou</b>	
FILING <b>October 29, 2001</b>	GROUP <b>1732</b>

## U.S. PATENT DOCUMENTS

[illegible]

## FOREIGN PATENT DOCUMENTS

[illegible]

**OTHER DOCUMENTS** (Including Author, Title, Date, Pertinent Pages, Etc.)

MOV		Aumiller et al., "Submicrometer Resolution Replication of Relief Patterns for Integrated Optics", J. Appl. Phys., Vol. 45, pp. 4557-4562, (1974)
MOV		Nisper, "Injection-molded replication of binary optic structures", SPIE v2600 Oct 23-24, 1995 p. 56-64 0227-786X

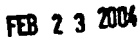
**EXAMINER**

M. Vargot

**DATE CONSIDERED**

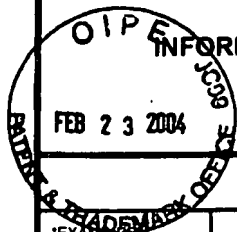
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GROUP	1732
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U6090-3SERIAL NO.  
10/046,594

Stephen Y. Chou

FILING  
October 29, 2001GROUP  
1732**U.S. PATENT DOCUMENTS**

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

**FOREIGN PATENT DOCUMENTS**

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

**OTHER DOCUMENTS** *(Including Author, Title, Date, Pertinent Pages, Etc.)*

W6V			Healey et al., "Photodeposition of Micrometer-scale polymer patterns on optical imaging Fibers" Science Vol. 269, August 1995, pp. 1078-1080.

EXAMINER  
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*7/2/07*

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Sheet 1 of \*P\*

Form 1449*	Atty. Docket No.: 600.426US2	Serial No. Unknown
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Stephen Y. Chou	
	Filing Date: Herewith	Group: Unknown

## U.S. PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date if Appropriate
MOV	3,743,842	07/03/1973	Smith, H.I., et al.	250	320	01/14/72
↑	4,310,743	01/12/1982	Seliger, R.L.	219	121 EB	09/24/79
↑	4,325,779	04/20/1982	Rossetti, J.J.	156	651	11/17/80
↑	4,383,026	05/10/1983	Hall, T.M.	430	325	08/24/81
↑	4,450,358	05/22/1984	Reynolds, G.O.	250	492.1	09/22/82
↑	4,498,009	02/05/1985	Reynolds, G.O.	250	452.1	09/22/82
↑	4,516,253	05/07/1985	Novak, W.T.	378	034	04/25/83
↑	4,552,615	11/12/1985	Amendola, A., et al.	158	659.1	05/21/84
↑	4,576,678	03/18/1986	Shibata, H.	156	643	09/13/84
↑	4,606,788	08/19/1986	Moran, P.L.	156	656	04/03/85
↑	4,731,155	03/15/1988	Napoli, L.S., et al.	156	643	04/15/87
↑	4,832,790	05/23/1989	Rossetti, J.J.	156	651	02/24/87
↓	5,277,749	01/11/1994	Griffith, J.H., et al.	156	643	10/17/91
MOV	5,861,113	01/19/1999	Choquette, S.J., et al.	264	1.24	08/01/96

## FOREIGN PATENT DOCUMENTS

Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
MOV	1196749	01/30/1988	European	G11B	7/26	
↑	244884	03/28/1986	European	B29C	33/64	
↑	401196749	08/08/1989	Japan	G11B	7/26	
↑	4255307	09/10/1992	Japan	B29C	33/38	
↑	4332694	08/05/1991	European	B41N	1/12	
↓	9117565	11/14/1991	PCT	H01L	21/00	
MOV	98/26913	06/25/1998	PCT	B29C	33/58	

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

MOV	Broere, et al., "250-A Linewidths with PMMA Electron Resist", <u>Applied Physics Letter 33 (5)</u> , 1978 American Institute of Physics, 392-394, (September 1, 1978)
↑	Chou, S.Y., et al., "Imprint Lithography with 25-Nanometer Resolution", <u>Science, Vol 272</u> , 85-87, (April 5, 1996)
↓	Early, K., et al., "Absence of Resolution Degradation in X-Ray Lithography for Wavelength from 4.5nm to 0.83nm", <u>Microelectronic Engineering 11</u> , Elsevier Science Publishers B.V., 317-321, (1990)
MOV	Fischer, et al., "10 nm Electron Beam Lithography and sub-50 nm Overlay Using a Modified Scanning Electron Microscope", <u>Applied Physics Letter 62 (23)</u> , 1993 American Institute of Physics, 2989-2991, (June 7, 1993)

Examiner

M. Vargab

Date Considered

7/2/07

\*Substitute Disclosure Statement Form (PTO-1449)

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Sheet 2 of \*P\*

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	Filing Date: Herewith	Group: Unknown

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

\*\*Examiner  
Initial

MOV	Hara, et al., "An Alignment Technique Using Diffracted Moire Signals", <u>J. Vac. Sci. Technol. B 7 (6)</u> , 1989 American Vacuum Society, 1977-1979, (Nov./Dec. 1989)
↑	Harmening, et al., "Molding of Threedimensional Microstructures by the Liga Process", <u>Proceedings IEEE: Micro Electro Mechanical Systems</u> , Travemunde, Germany, 202-207, (1992)
↓	Li, et al., "Molding of Plastic Components Using Micro-EDM Tools", <u>IEEE/CHMT International Electronics Manufacturing Technology Symposium</u> , 145-149, (1992)
MOV	Nomura, et al., "Moire Alignment Technique for the Mix and Match Lithographic System", <u>J. Vacuum Society Technol. B 6 (1)</u> , American Vacuum Society, 394-398, (Jan/Feb 1988)

Examiner

*M. Vargot*

Date Considered

7/2/07

\*Substitute Disclosure Statement Form (PTO-1449)

\*\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 209; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.